



## INFORMATION DISCLOSURE STATEMENT

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## U.S. PATENT DOCUMENTS

EXAMINER INITIALS	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB-CLASS	FILING DATE (IF APPROPRIATE)

## FOREIGN PATENT DOCUMENTS

EXAMINER INITIALS	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION	
							YES	NO
RK	A	EP 0 299 875	01/18/89	European Patent Office			—	—
RK	B	01147374	06/09/89	Japan			Abstract	—
RK	C	EP 0 466 274	01/15/92	European Patent Office			—	—
RK	D	DE 43 01 420	06/24/93	Germany			—	—
RK	E	WO 94/11745	05/26/94	WIPO			—	—
RK	F	07199219	08/04/95	Japan			Abstract	—
RK	G	8-15318	01/19/96	Japan			—	—
RK	H	DE 196 48 475	06/05/97	Germany			—	—
RK	I	EP 0 899 538	03/03/99	European Patent Office			—	—

## OTHER DOCUMENTS

RK	J	Fujii, et al., "Micropattern measurement with an atomic force microscope", <u>Journal of Vacuum Science &amp; Technology: Part B</u> , Vol. 9, No. 2, pp. 666-669 (March/April 1991).						
RK	K	Hong, et al., "Design and Fabrication of a Monolithic High-Density Probe Card for High-Frequency On-Water Testing", <u>Institute of Electrical and Electronics Engineers</u> , pp. 289-292 (December 3, 1989).						
RK	L	Koops, et al., "Constructive three-dimensional lithography with electron-beam induced deposition for quantum effect devices", <u>Journal of Vacuum Science &amp; Technology B (Microelectronics Processing and Phenomena)</u> , Vol. 11, No. 6, pp. 2286-2289 (November/December 1993).						
RK	M	Koops, et al., "Conductive dots, wires, and supertips for field electron emitters produced by electron-beam induced deposition on samples having increased temperature", <u>Journal of Vacuum Science &amp; Technology B (Microelectronics Processing and Phenomena)</u> , Vol. 14, No. 6, pp. 4105-4109 (November/December 1996).						
RK	N	Lee, et al., "High-Density Silicon Microprobe Arrays for LCD Pixel Inspection", <u>Institute of Electrical and Electronics Engineers</u> , pp. 429-434 (February 11, 1996).						
RK	O	Niu, et al., "Double-tip scanning tunneling microscope for surface analysis", <u>Physical Review B</u> , Vol. 51, No. 8, pp. 5502-5505 (February 15, 1995).						
RK	P	Shi, et al., "New method of calculating the correction factors for the measurement of sheet resistivity of a square sample with a square four-point probe", <u>Rev. Sci. Instrum.</u> , Vol. 68, No. 4, pp. 1814-1817 (April 1997).						
RK	Q	Smits, "Measurement of Sheet Resistivities with the Four-Point Probe", <u>The Bell System Technical Journal</u> , Vol. 37, pp. 711-718 (May 1958).						

Examiner:

Date Considered:

5-11-06